

IN THE SPECIFICATION:

Paragraph beginning on page 3, at prenumbered line 11, has been deleted in its entirety as follows:

~~An apparatus for sealing a vacuum chamber of the present invention is applied to treatment process, which is mounted on vacuum thin film coating treatment equipments of workpieces such as semiconductor wafers, liquid crystal substrates, or photoelectric semiconductor devices.~~

Paragraph beginning on page 3, at prenumbered line 15, has been amended as follows:

As shown in Fig. 1 and Fig. 2, an apparatus 100 for sealing a vacuum chamber comprises an elevating mechanism, a sealing mechanism, a door 140 and a shell body 150 for mounting on a vacuum chamber wall 10 of a vacuum chamber. The elevating mechanism is configured for vertically moving the door 140 up and down, which comprises a plurality of long stroke cylinders 110 and first piston rods 111. In this embodiment there are two sets of long stroke cylinders 110. One end of each first ~~piston~~ piston rod 111 movably connects with the corresponding long stroke cylinder 110 and the other end of the first piston rod 111 is fixedly connected with the frame elevator 130 of the sealing mechanism for vertically moving the frame elevator 130 to a predetermined point, also the door 140 connects with the frame elevator 130 by direction-changing mechanism 160 for moving up or down synchronously. The long stroke cylinders 110 make the first piston rods 111 linearly move to a predetermined location so the frame elevator 130 may move between two locations along a linear direction (as shown in Fig. 2 and Fig. 4).

Paragraph beginning on page 4, at prenumbered line 2, has been amended as follows:

The door 140 is installed inside the shell body 150 with proper shape such as rectangle, square or circle. In this embodiment the door 140 is in square configuration. The flat type shell body 150 has an opening 151 corresponding to the

door 140. A guide plate 152 is fixed at one side of the shell 150, which has through holes for the guide stems 131 and the second piston rods ~~121~~of 121 of the sealing mechanism moving in and passing through the shell body 150.

Paragraph beginning on page 4, at prenumbered line 8, has been amended as follows:

The sealing mechanism is configured for horizontally moving the door 140 to seal a vacuum chamber, which comprises a frame elevator 130 and a support frame 132. Two guide stems 131 are fixedly equipped at the inner side of the frame elevator 130 ~~with one ends~~ at respective first ends and pass through the guide plate 152 of shell 150, then guide stems 131 are mounted on the support frame 132 inside the shell 150 ~~with the other ends~~ at respective second ends thereof. A plurality of narrow openings 133 are formed on the support frame 132 to provide moving spaces of pivoting axes at first ends 162a of sliding blocks 162 of direction-changing mechanisms 160 (as shown in Fig. 3). The support frame 132 has a fixed across bar 134 with supporting axes 136 for pivoting the levers 123. Besides, the O-rings 135 are fitted around the through holes of guide plate 152 where guide stems 131 and second piston rods 121 pass through in order to enhance air-tight and cushioning effect of mechanical movement.

Application No. 10/050,180

IN THE DRAWINGS:

Enclosed are replacement new formal drawings of Figures 1, 2 and 4, accompanied by a LETTER TO THE OFFICIAL DRAFTSPERSON. In Figures 1, 2 and 4, the reference number --100-- has been added.